In re: Krzysztof Nauka et al.

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## Amendments to the Claims:

This listing of claims replaces all prior versions, and listings, of claims of this application:

## **Listing of Claims:**

The following listing of claims will replace all prior versions, and listings, of claims in the application.

## 1.-8. (Cancelled)

9. (Currently amended) A data storage device comprising a conductive probe having a tip; a substrate including a semiconductor portion; a data storage medium including a layer of poled ferroelectric material for storing data, the <u>poled</u> ferroelectric layer on the substrate, between the tip and the substrate, the semiconductor portion and the <u>poled</u> ferroelectric layer forming an electrical junction; and a circuit <u>for causing configured to provide a constant voltage bias to</u> the conductive probe <u>as the conductive probe is dragged across multiple bits stored in the</u> poled ferroelectric layer to perform block and bulk erasure operations.

## 10. (Cancelled)

11. (Currently amended) A data storage device comprising a conductive probe having a tip; a substrate including a semiconductor portion; a data storage medium including a layer of poled ferroelectric material for storing data, the <u>poled</u> ferroelectric layer on the substrate, between the tip and the substrate, the semiconductor portion and the <u>poled</u> ferroelectric layer forming an electrical junction; and a read circuit for using the probe to sense changes in capacitance or leakage current of the <u>electrical</u> junction <u>between the semiconductor portion and the poled</u> ferroelectric layer.

12.-27.(Cancelled)

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28. (Currently amended) A method of reading information from a ferroelectric layer that is on a semiconductor substrate and forms an electrical junction with the semiconductor substrate, the method comprising:

scanning a surface of the ferroelectric layer with a probe having a sharp tip, the tip having a diameter of several nanometers; and

using the probe and the semiconductor substrate to detect polarity reversals at designated locations on the ferroelectric layer, each polarity reversal at a designated location indicating a first stored value at that designated location, each non-reversal of polarity at an expected location indicating a second logic value stored at that designated location;

wherein the probe is used to sense changes in <del>capacitance or</del> leakage current of the <u>electrical</u> junction <u>between the semiconductor substrate and the ferroelectric</u> <u>layer</u>.

29.–37. (Cancelled)